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(71)Applicant : KOKUSAI ELECTRIC CO LTD

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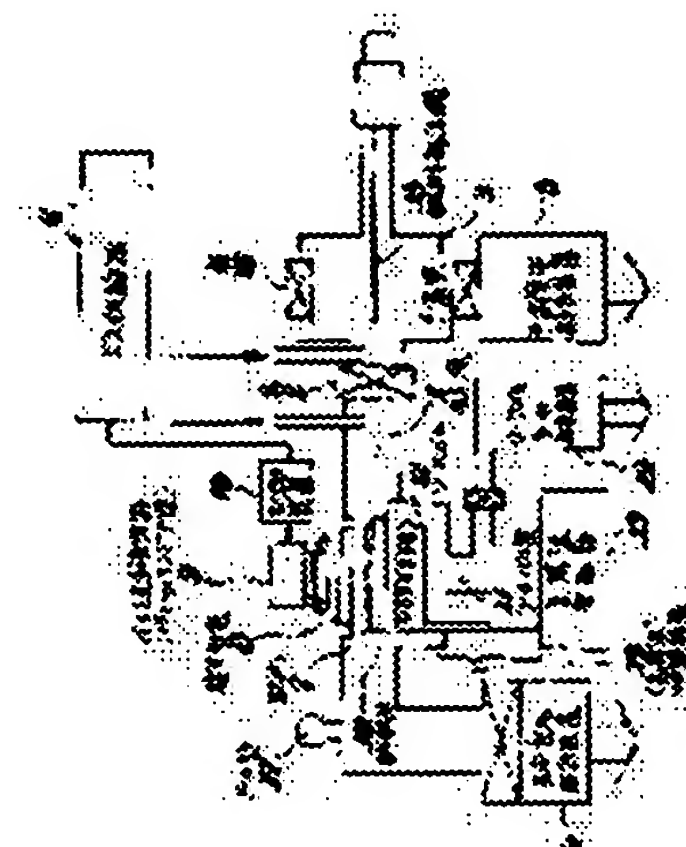
(72)Inventor : MUROTA JUNICHI
ONO SHOICHI
SAKURABA MASAO
MIKOSHIBA YOSHIO
KUROKAWA HARUSHIGE
IKEDA FUMIHIDE

(54) METHOD AND APPARATUS FOR VAPOR GROWTH

(57)Abstract:

PURPOSE: To form a thin film as an atomic layer on a specimen.

CONSTITUTION: In a state that a specimen 7 arranged inside a reaction chamber 1 is exposed to a raw-material gas introduced from a gas supply source 6, the specimen 7 is irradiated with pulse light by using a pulse-light irradiation light source 9. Thereby, a thin film as a monoatomic layer or as a layer of several atoms is grown at each irradiation operation.



LEGAL STATUS

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